

ACKNOWLEDGEMENT RECEIPT

Electronic Version 1.1

Stylesheet Version v1.1.1

Title of Invention

HIGH-PRESSURE PROCESSING CHAMBER FOR A SEMICONDUCTOR WAFER

Submission Type : Information Disclosure
Statement

Application Number:

10/680783



EFS ID:

88501

Server Response:

Confirmation Code	Message
ISVR1	Submission was successfully submitted - Even if Informational or Warning Messages appear below, please do not resubmit this application
ICON1	5859
USPTOEFSNot	For assistance with e-filing a patent application, contact the Patent Electronic Business Center: Toll-Free Number:1(866) 217-9197 Website: http://www.uspto.gov/ebc/

First Named Applicant: William Jones

Attorney Docket Number:

Timestamp: 2005-07-19 19:30:36 EDT

From: US

File Listing:

Doc. Name	File Name	Size (Bytes)	Date Produced (yyyymmdd)
us-ids	SSI04001-usldst.xml	3804	2005-07-19
us-ids	us-ids.dtd	7763	2005-07-19
us-ids	us-ids.xsl	12026	2005-07-19
package-data	SSI04001-pkda.xml	1706	2005-07-19
package-data	package-data.dtd	27025	2005-07-19
package-data	us-package-data.xsl	19263	2005-07-19
Total files size		71587	

Message Digest: 7e94a6197aadd808cccec6cd75aba774617ece89e

Digital Certificate Holder
Name:

cn=Thomas B.
Haverstock,ou=Registered
Attorneys,ou=Patent and
Trademark
Office,ou=Department of
Commerce,o=U.S.
Government,c=US